

## AMENDMENTS IN THE CLAIMS

*Please amend the claims as follows:*

1. (cancelled)
2. (currently amended) An interferometric method for measuring, said method comprising:  
generating a first coherent light beam and a second coherent light beam;  
reflecting at least said first coherent light beam from a first region into a first return  
beam and reflecting said second coherent light beam from a second region into a second return  
beam;  
measuring at least a first reflectivity of said first region;  
determining a topography-dependent phase shift of said first return beam and said  
second return beam based on said first reflectivity;  
measuring a height based on said topography-dependent phase shift;  
~~The method of claim 1, further comprising:~~  
comparing said first reflectivity and a second reflectivity of said second region; and  
using a total phase shift of said first return beam and said second return beam for said  
height measurement, if said first reflectivity and said second reflectivity are equal.
3. (currently amended) The method of claim [[1]] 2, wherein the topography-dependent phase shift is determined based on an optical property of an area covered by said first region.
4. (currently amended) The method of claim [[1]] 2, wherein said determining step further comprises determining the topography-dependent phase shift with reference to a curve relating said first reflectivity to a material-dependent phase shift.
5. (currently amended) The method of claim [[1]] 2, wherein said determining step further comprises employing a reflectivity of a second region on a reference surface having known optical properties.
6. (currently amended) The method of claim [[1]] 2, wherein said determining step further comprises measuring a second reflectivity of a second region on said first surface; and  
determining the topography-dependent phase shift based on said first reflectivity and said second reflectivity.

7. (currently amended) The method of claim [[1]] 2, wherein said determining step further comprises determining a fringe visibility for use in determining said topography-dependent phase shift.

8. (currently amended) The method of claim [[1]] 2, wherein said determining step further comprises determining a topography dependent phase shift through mathematical relationships, comprising:

$$\Delta\phi_h = \Delta\phi_T - \Delta\phi_m;$$

$$\Delta\phi_m = \arcsin(\alpha\beta);$$

$$\alpha = \frac{r_1 r_2 \sin(\phi_2 - \phi_1)}{|(r_1)^2 - (r_2)^2|};$$

$$\beta = \frac{1}{2V} \frac{(R_1)^2 - (R_2)^2}{(R_1)^2 + (R_2)^2};$$

wherein :

$\Delta\phi_h$  is a topography - dependent \_phase \_shift;

$\Delta\phi_T$  is a total \_phase \_shift;

$\Delta\phi_m$  is a material - dependent \_phase \_shift;

$r_1$  is a reflection \_coefficient \_of \_first \_area;

$r_2$  is a reflection \_coefficient \_of \_sec ond \_area;

$\phi_1$  is a phase \_shift \_caused \_by \_reflection \_from \_first \_area;

$\phi_2$  is a phase \_shift \_caused \_by \_reflection \_from \_sec ond \_area;

$R_1$  is a reflectivity \_of \_first \_region;

$R_2$  is a reflectivity \_of \_sec ond \_region; and

$V$  is a fringe \_visibility.

9. (currently amended) The method of claim [[1]] 2, wherein:

the determining step further comprises calculating a material-dependent phase shift based on a first optical property, a second optical property, and a first reflectivity of a first region; and

the determining step further comprises determining a topography-dependent phase shift by subtracting a material-dependent phase shift from a total phase shift of a first reflected coherent light beam and a second reflected coherent light beam.

10. (cancelled)

11. (currently amended) A machine-readable medium having a plurality of instructions processable by a machine embodied therein, wherein said plurality of instructions, when processed by said machine, causes said machine to perform a method, said method comprising:

~~The computer program product of claim 10, further comprising:~~

generating a first coherent light beam and a second coherent light beam;

reflecting at least said first coherent light beam from a first region into a first return beam and reflecting said second coherent light beam from a second region into a second return beam;

measuring at least a first reflectivity of said first region;

determining a topography-dependent phase shift of said first return beam and said second return beam based on said first reflectivity;

measuring a height based on said topography-dependent phase shift;

~~instructions on the computer-readable medium for comparing said first reflectivity and a second reflectivity of said second region; and~~

~~instructions on the computer-readable medium for using a total phase shift of said first return beam and said second return beam for said height measurement, if said first reflectivity and said second reflectivity are equal.~~

12. (currently amended) ~~The computer program product~~ machine-readable medium of claim [[10]] 11, wherein said ~~instructions for step of~~ determining said topography-dependent phase shift further comprises instructions for determining said topography-dependent phase shift based on an optical property of an area covered by said first region.

13. (currently amended) ~~The computer program product~~ machine-readable medium of claim [[10]] 11, wherein said determining ~~instructions step~~ further comprises instructions for determining said topography-dependent phase shift with reference to a curve relating said first reflectivity to a material-dependent phase shift.

14. (currently amended) ~~The computer program product~~ machine-readable medium of Claim [[10]] 11, wherein said determining ~~instructions step~~ further comprises instructions for employing a reflectivity of a second region on a reference surface having known optical properties.

15. (currently amended) ~~The computer program product~~ machine-readable medium of claim [[10]] 11, wherein said determining ~~instructions step~~ further comprises:

~~instructions for~~ measuring a second reflectivity of a second region on said first surface;  
and

~~instructions on the computer-readable medium for~~ determining the topography-dependent phase shift based on said first reflectivity and said second reflectivity.

16. (currently amended) The ~~computer program product~~ machine-readable medium of claim [[10]] 11, wherein said determining ~~instructions step~~ further comprises ~~instructions for~~ determining a fringe visibility for use in determining said topography-dependent phase shift.

17. (currently amended) The ~~computer program product~~ machine-readable medium of claim [[10]] 11, wherein said determining ~~instructions step~~ further comprises ~~instructions for~~ determining a topography dependent phase shift through mathematical relationships, comprising:

$$\Delta\phi_h = \Delta\phi_T - \Delta\phi_m;$$

$$\Delta\phi_m = \arcsin(\alpha\beta);$$

$$\alpha = \frac{r_1 r_2 \sin(\phi_2 - \phi_1)}{|(r_1)^2 - (r_2)^2|};$$

$$\beta = \frac{1}{2V} \frac{(R_1)^2 - (R_2)^2}{(R_1)^2 + (R_2)^2};$$

wherein :

$\Delta\phi_h$  is a topography - dependent phase shift;

$\Delta\phi_T$  is a total phase shift;

$\Delta\phi_m$  is a material - dependent phase shift;

$r_1$  is a reflection coefficient of first area;

$r_2$  is a reflection coefficient of second area;

$\phi_1$  is a phase shift caused by reflection from first area;

$\phi_2$  is a phase shift caused by reflection from second area;

$R_1$  is a reflectivity of first region;

$R_2$  is a reflectivity of second region; and

$V$  is a fringe visibility.

18. (currently amended) The ~~computer program product~~ machine-readable medium of claim [[10]] 11, wherein:

the determining ~~instructions step~~ further comprises ~~instructions for~~ calculating a material-dependent phase shift based on a first optical property, a second optical

property, and a first reflectivity of a first region; and

the determining ~~instructions~~ step further comprises ~~instructions~~ for determining a topography-dependent phase shift by subtracting a material-dependent phase shift from a total phase shift of a first reflected coherent light beam and a second reflected coherent light beam.

19. (cancelled)

20. (currently amended) An interferometer for measuring height, said interferometer comprising:

~~The interferometer of claim 19, further comprising:~~

means for generating a first coherent light beam and a second coherent light beam;

means for reflecting at least said first coherent light beam from a first region into a first return beam and reflecting said second coherent light beam from a second region into a second return beam;

means for measuring at least a first reflectivity of said first region;

means for determining a topography-dependent phase shift of said first return beam and said second return beam based on said first reflectivity;

means for measuring a height based on said topography-dependent phase shift;

means for comparing said first reflectivity and a second reflectivity of said second region; and

means for using a total phase shift of said first return beam and said second return beam for said height measurement, if said first reflectivity and said second reflectivity are equal.

21. (currently amended) The interferometer of claim ~~[[19]]~~ 20, wherein said means for determining said topography-dependent phase shift further comprise means for determining said topography-dependent phase shift based on an optical property of an area covered by said first region.

22. (currently amended) The interferometer of claim ~~[[19]]~~ 20, wherein said determining means further comprise means for determining said topography-dependent phase shift with reference to a curve relating said first reflectivity to a material-dependent phase shift.

23. (currently amended) The interferometer of claim [[19]] 20, wherein said determining means further comprise means for employing a reflectivity of a second region on a reference surface having known optical properties,

24. (currently amended) The interferometer of claim [[19]] 20, wherein said determining means further comprise means for measuring a second reflectivity of a second region on said first surface; and

means for determining the topography-dependent phase shift based on said first reflectivity and said second reflectivity.

25. (currently amended) The interferometer of claim [[19]] 20, wherein said determining means further comprise means for determining a fringe visibility for use in determining said topography-dependent phase shift.

26. (currently amended) The interferometer of claim [[19]] 20, wherein said determining means further comprise means for determining a topography dependent phase shift through mathematical relationships, comprising:

$$\Delta\phi_h = \Delta\phi_T - \Delta\phi_m;$$

$$\Delta\phi_m = \arcsin(\alpha\beta);$$

$$\alpha = \frac{r_1 r_2 \sin(\phi_2 - \phi_1)}{|(r_1)^2 - (r_2)^2|};$$

$$\beta = \frac{1}{2V} \frac{(R_1)^2 - (R_2)^2}{(R_1)^2 + (R_2)^2};$$

wherein :

$\Delta\phi_h$  is a topography - dependent\_phase\_shift;

$\Delta\phi_T$  is a total\_phase\_shift;

$\Delta\phi_m$  is a material - dependent\_phase\_shift;

$r_1$  is a reflection\_coefficient\_of\_first\_area;

$r_2$  is a reflection\_coefficient\_of\_second\_area;

$\phi_1$  is a phase\_shift\_caused\_by\_reflection\_from\_first\_area;

$\phi_2$  is a phase\_shift\_caused\_by\_reflection\_from\_second\_area;

$R_1$  is a reflectivity\_of\_first\_region;

$R_2$  is a reflectivity\_of\_second\_region; and

$V$  is a fringe\_visibility.

27. (currently amended) The interferometer of claim ~~[[19]]~~ 20, wherein:

the determining means further comprise means for calculating a material-dependent phase shift based on a first optical property, a second optical property, and a first reflectivity of a first region; and

the determining means further comprise means for determining a topography-dependent phase shift by subtracting a material-dependent phase shift from a total phase shift of a first reflected coherent light beam and a second reflected coherent light beam.